

VIA FACSIMILE NO. (703) 872-9310

PATENT
MIC04 P-106

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Examiner : George A. Goudreau
Group : 1763
Confirmation No. : 4253
Applicant : Iimad Mahawili, PhD
Serial No. : 09/488,309
Filed : January 20, 2000
For : REACTOR WITH REMOTE PLASMA SYSTEM AND
METHOD OF PROCESSING A SEMICONDUCTOR
SUBSTRATE

Commissioner for Patents
P.O. Box 1450
Alexandria VA 22313-1450

Dear Sir:

RESPONSE

In response to the Office Action mailed July 17, 2003, having a three-month period of response ending October 17, 2003, Applicant submits herewith a Petition and Fee for a two-month Extension of Time and amend their application as follows: